

ABSTRACT OF THE DISCLOSURE

To provide a substrate treating apparatus for keeping a substrate in contact with a treating tool under a prescribed pressure.

According to this invention, a bracket 10 which is hoisted or lowered by a hoisting/lowering device 15 is provided with a treating tool 3 for carrying out the treatment such as cleaning for the surface of a substrate in contact with the surface under a prescribed pressure therefor, an operating shaft 4 with the treating tool 3 attached thereto, a holding member 6 for holding the operating shaft 4 freely only in its rotating direction, a servomotor 11 coupled to the holding member 6, for moving up and down the operating shaft 4, and a rotary motor 8 coupled with the operating shaft 4 through a pin joint 9. Separately from the hoisting/lowering device 15 for the bracket 10, the servo motor 11 for moving up and down the operating shaft 4 is provided. The servo motor is excited according to the difference between the weight of the operating shaft 4 inclusive of the treating tool 3 and a prescribed contact pressure or weight so that an output torque is applied to the operating shaft 4 to cancel the weight of the operating shaft 4, thereby keeping the treating tool 3 in contact with the substrate surface with the weight corresponding to the prescribed contact pressure.